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-	276	703/13.ccor.	USPAT;	2004/10/25 12:53
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7.	(pub-date > 1949 and pub-date < 2002 and FULL-TEXT(kalman filter) and FULL-TEXT(model)) and adaptive [All Sources(- All Sciences -)]	1274
6.	pub-date > 1949 and pub-date < 2002 and FULL-TEXT(kalman filter) and FULL-TEXT(model) [All Sources(- All Sciences -)]	3432
5.	(pub-date > 1949 and pub-date < 2002 and FULL-TEXT(scalpel) and FULL-TEXT(model)) and kalman [All Sources(- All Sciences -)]	7
4.	pub-date > 1949 and pub-date < 2002 and FULL-TEXT(scalpel) and FULL-TEXT(model) [All Sources(- All Sciences -)]	4075
3.	pub-date > 1949 and pub-date < 2002 and FULL-TEXT(adaptive kalman filter) and FULL-TEXT(model) [All Sources(-All Sciences -)]	67
2.	pub-date > 1949 and pub-date < 2002 and FULL-TEXT(lithography or photolithography) and FULL-TEXT(adaptive) [All Sources(- All Sciences -)]	153
1.	pub-date > 1949 and pub-date < 2002 and FULL-TEXT(lithography or photolithography) and FULL-TEXT(kalman) [All Sources(- All Sciences -)]	14

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	2 Subject Index
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O- Access the IEEE Member	[Abstract] [PDF Full-Text (282 KB)] IEEE JNL
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Pages:1417 - 1432

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Pages: 1628 - 1647

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Pages:99 - 102

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Pages:Ind-13 - Ind-50

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Pages:0_3 - 0_53

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Pages:1417 - 1432

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Pages:33 - 103

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20 Back cover

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Pages:0 - 0

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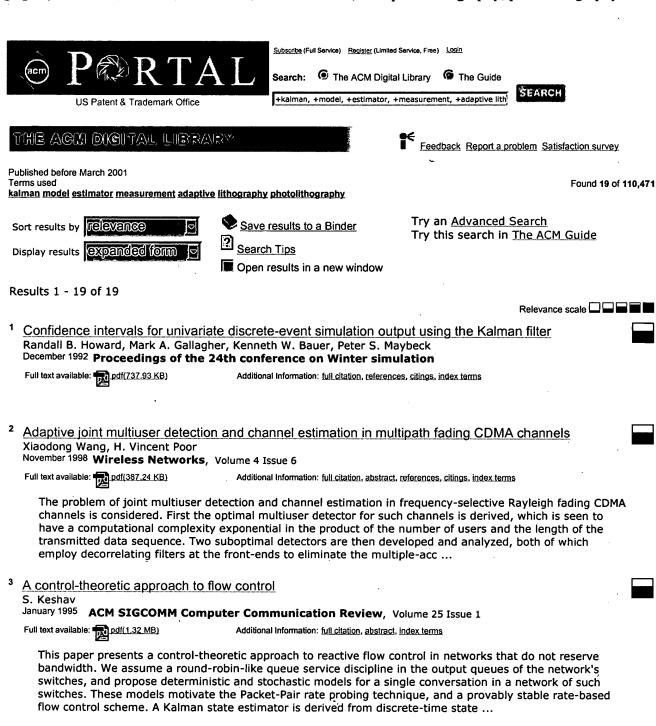
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S. S. Beauchemin, J. L. Barron

September 1995 ACM Computing Surveys (CSUR), Volume 27 Issue 3

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Two-dimensional image motion is the projection of the three-dimensional motion of objects, relative to a visual sensor, onto its image plane. Sequences of time-orderedimages allow the estimation of projected two-dimensional image motion as either instantaneous image velocities or discrete image displacements. These are usually called the optical flow field or the image velocity field. Provided that optical flow is a reliable approximation to two-dimensional ...

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Greg Welch, Gary Bishop

August 1997 Proceedings of the 24th annual conference on Computer graphics and interactive techniques

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Keywords: Kalman filter, autocalibration, calibration, delay, feature tracking, latency, sensor fusion, virtual environments tracking

A control-theoretic approach to flow control

Srinivasan Keshav

August 1991 ACM SIGCOMM Computer Communication Review, Proceedings of the conference on Communications architecture & protocols, Volume 21 Issue 4

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Real-time estimation of the parameters of long-range dependence

Matthew Roughan, Darryl Veitch, Patrice Abry

August 2000 IEEE/ACM Transactions on Networking (TON), Volume 8 Issue 4

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Keywords: Hurst parameter, estimation, fractal, long-range dependence, on-line, real-time, self-similar, traffic modeling, wavelets

Subspace methods for blind joint channel estimation and multiuser detection in CDMA systems

Xiaodong Wang, H. Vincent Poor

January 2000 Wireless Networks, Volume 6 Issue 1

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Recently developed subspace techniques for blind adaptive multiuser detection are briefly reviewed first. In particular, blind methods based on signal subspace tracking for adapting linear multiuser detectors in AWGN CDMA channels are considered, as well as extensions of these techniques to frequency selective fading channels, dispersive channels, and antenna array spatial processing. In addition, subspace‐ based nonlinear adaptive techniques for robust blind multiuser detection in non& ...

Parameter identification methods for metamodeling simulations

Don Caughlin

November 1996 Proceedings of the 28th conference on Winter simulation

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10 Improving static and dynamic registration in an optical see-through HMD

Ronald Azuma, Gary Bishop

July 1994

Proceedings of the 21st annual conference on Computer graphics and interactive techniques

Full text available: pdf(321.33 KB) ps(1.65

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In Augmented Reality, see-through HMDs superimpose virtual 3D objects on the real world. This technology has the potential to enhance a user's perception and interaction with the real world. However, many Augmented Reality applications will not be accepted until we can accurately register virtual objects with their real counterparts. In previous systems, such registration was achieved only from a limited range of viewpoints, when the user kept his head still. This paper offers improved regi ...

Keywords: augmented reality, calibration, registration

3D position, attitude and shape input using video tracking of hands and lips

Andrew Blake, Michael Isard

July 1994 Proceedings of the 21st annual conference on Computer graphics and interactive techniques

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Recent developments in video-tracking allow the outlines of moving, natural objects in a video-camera input stream to be tracked live, at full video-rate. Previous systems have been available to do this for specially illuminated objects or for naturally illuminated but polyhedral objects. Other systems have been able to track nonpolyhedral objects in motion, in some cases from live video, but following only centroids or key-points rather than tracking whole curves. The system described here ...

¹² Stochastic version of second-order (Newton-Raphson) optimization using only function measurements James C. Spall

December 1995 Proceedings of the 27th conference on Winter simulation

Full text available: pdf(579.39 KB)

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¹³ A frequency-domain analysis of head-motion prediction

Ronald Azuma, Gary Bishop

September 1995 Proceedings of the 22nd annual conference on Computer graphics and interactive techniques

Full text available: pdf(401.93 KB) ps(629.89 KB)

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Keywords: HMD, augmented reality, delay compensation, spectral analysis

¹⁴ Ada Compiler Evaluation Capability (ACEC) data analysis: an overview

Air Force Systems Command

January 1990 ACM SIGAda Ada Letters, Proceedings of the working group on Ada performance issues 1990, Volume X Issue 3

Full text available: pdf(1.08 MB)

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¹⁵ Papers: ESW4: enhanced scheme for WWW computing in wireless communication environments Stathes Hadjiefthymiades, Lazaros Merakos

October 1999 ACM SIGCOMM Computer Communication Review, Volume 29 Issue 5

Full text available: pdf(1.18 MB)

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Mobile computing is considered of major importance to the computing industry for the forthcoming years due to the progress in the wireless communications domain. In this paper, we present a proxy-based architecture, called ESW4, which manages to accelerate Web browsing in wireless CPNs. Proxy caches, maintained in base stations, are constantly relocated to accompany the roaming user. We discuss a cache management scheme involving the relocation of full caches to the most candidate cells but also ...

On hop-by-hop rate-based congestion control

Partho Pratim Mishra, Hemant Kanakia, Satish K. Tripathi

April 1996 IEEE/ACM Transactions on Networking (TON), Volume 4 Issue 2

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Real-time APL prototype of a GPS system

Henry M. Beisner, Jack G. Rudd, Robert H. Benner

June 1996 ACM SIGAPL APL Quote Quad, Proceedings of the conference on Designing the future,

Volume 26 Issue 4

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The Global Positioning System (GPS) consists of a constellation of 24 high-altitude satellites with very accurate atomic clocks, along with a global network of satellite tracking stations and sophisticated ground processing stations, that together provide precise navigation coordinates to any user who possesses a small, readily available GPS receiver. The precision that is achieved depends on[1] the number of GPS satellites in view of the user and the geometries involved;[2] the design of the use ...

18 The ControlShell component-based real-time programming system, and its application to the Marsokhod Martian Rover

Stan Schneider, Vincent Chen, Jay Steele, Gerardo Pardo-Castellote

November 1995 ACM SIGPLAN Notices, Proceedings of the ACM SIGPLAN 1995 workshop on Languages, compilers, & tools for real-time systems, Volume 30 Issue 11

Full text available: pdf(1.39 MB)

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Real-time system software is notoriously hard to share and reuse. This paper walks through the methodology and application of ControlShell, a component-based programming system for real-time system software development. ControlShell combines graphical system-building tools, an execution-time configuration manager, a real-time matrix package, and an object name service into an integrated development environment. It targets complex systems that require on-line reconfiguration and strategic control ...

¹⁹ The CMUnited-97 robotic soccer team: perception and multiagent control Manuela Veloso, Peter Stone, Kwun Han

May 1998 Proceedings of the second international conference on Autonomous agents

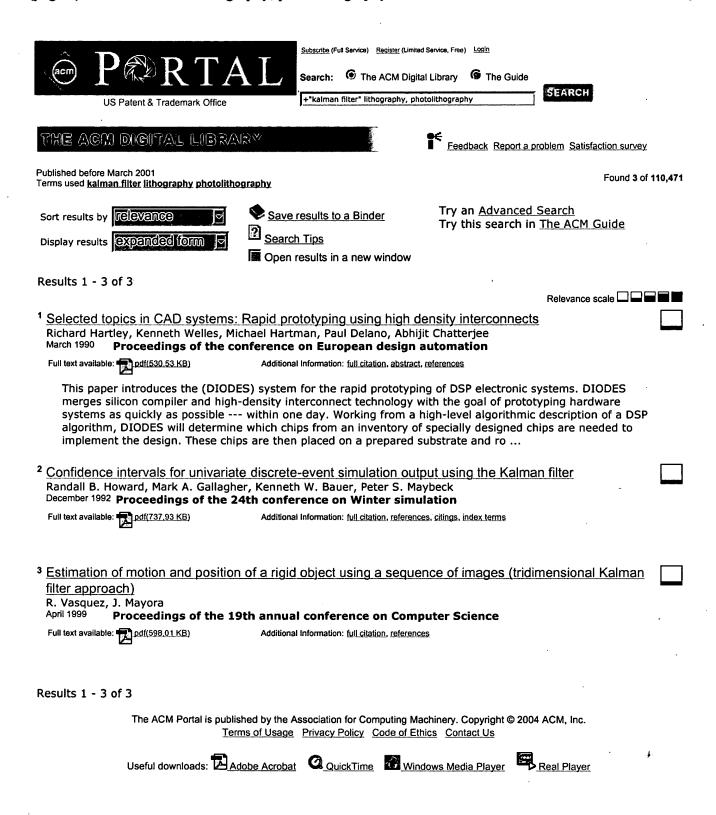
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Smoothing Of Noisy Ar Signals Using An Adaptive - Kalman Filter Gerhard (Correct)

1 Smoothing Of Noisy Ar Signals Using An Adaptive Kalman Filter Gerhard Doblinger Institut Fur www.nt.tuwien.ac.at/nthft/dipl_diss_veroeff/papers/db_eusip98pap.ps

An Adaptive Procedure - For Carrier Phase-Based (2001) (Correct) related to the physical environment. An **adaptive Kalman filter** has been proposed for real-time www.gmat.unsw.edu.au/snap/staff/../publications/dai etal2001i.pdf

An Adaptive Kalman Filter For The Enhancement Of Noisy AR Signals - Doblinger (1998) (Correct) 31-June 3, 1998, Monterey, California 1 An **Adaptive Kalman Filter** For The Enhancement Of Noisy Ar Signals www.nt.tuwien.ac.at/nthft/dipl_diss_veroeff/papers/db_iscas98.ps

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An Adaptive Stochastic State Observer In The Presence Of .. - Ludmila Mihaylova Nikola (1999) (Correct), P I 0 D I e ,0 3.2 Augmented **Adaptive Kalman Filter** The parameter estimates, computed by the www.mech.kuleuven.ac.be/~lmihaylo/avt99.pdf

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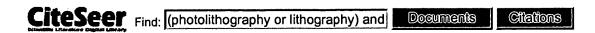
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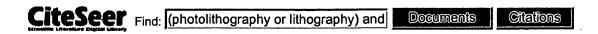
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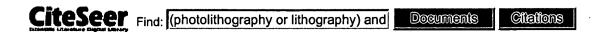
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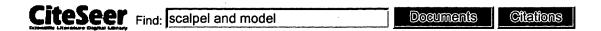
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Projection Electron Beam for Sub -Optical Lithography" presented at EIPBN '97, 27th -30th May, SPIE 3048 (1997)42 L. R. Harriott, SCALPEL Projection Electron Beam for Sub -Optical W. M. Simpson, R. Tarascon, and G. P. Watson, SCALPEL masks "BACUS/SPIE (1994)44 JW. K. 143.129.203.3/visielab/exstaff/jedrasik/../../theses/jedrasik/chap1bib.pdf

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